

In the Specification:

Please amend page 4, paragraph 4 as follows:

This and other advantages are achieved by the focussing lenses ~~according to claim 1 and 36~~, the charged particle beam device ~~according to claim 21~~, and the methods ~~according to claim 26, 37 and 38~~ of inspecting or structuring a specimen by means of a charged particle beam according to the present invention.

Please amend page 4, paragraph 5 as follows:

Further advantages, features, aspects, and details of the invention are evident from ~~the dependent claims~~, the description and the accompanying drawings. ~~The claims are intended to be understood as a first non-limiting approach of defining the invention in general terms.~~

Please amend page 4, paragraph 6 as follows:

The invention ~~according to claim 1~~ includes a focussing lens for focussing a charged particle beam onto a specimen at a predetermined landing angle comprising at least a first electrode having a first aperture to generate a focussing electric field for focussing the charged particle beam onto the specimen, and a correcting electrode having a curved surface to compensate for landing angle dependent distortions of the focussing electric field caused by the specimen.

Please amend page 7, paragraph 4 as follows:

The present invention also refers to a charged particle beam device ~~according to claim 24~~ which includes a charged particle beam source and a focusing lens. The charged particle beam device with the focussing lens ~~according to any one of the claims 1 to 26~~ is capable of inspecting or structuring a specimen at landing angles that deviate from 90 degrees with high spatial resolution.

Please amend page 8, paragraph 3 as follows:

The present invention also refers to a method of inspecting or structuring a specimen ~~according to claim 26. According to claim 26, the method of inspecting or structuring a specimen~~ by means of a charged particle beam which includes the steps of providing a charged particle beam device having a correcting electrode; inspecting or structuring the specimen at a first landing angle at a first correcting electrode voltage applied to the correcting electrode; and inspecting or structuring the specimen at a second landing angle at a second correcting electrode voltage applied to the correcting electrode.

Please amend page 10, paragraph 3 as follows:

The present invention also refers to a method of inspecting or structuring a specimen ~~according to claim 27. According to claim 27, the method of inspecting or structuring a specimen~~ by means of a charged particle beam which includes the steps of providing a charged particle beam device having at least a first electrode and a correcting electrode; inspecting or structuring the specimen at a first landing angle with the correcting electrode at a first position with respect to the at least first electrode; and inspecting or structuring the specimen at a second landing angle with the correcting electrode at a second position with respect to the at least first electrode.

Please amend page 12, paragraph 1 as follows:

In the description of the detailed embodiments according to the invention below, the numbers refer to the enclosed figures Fig.1a and 1b, Fig. 2a and 2b, Fig. 3A, 3B, 3C and 3D and to Fig. 4. The figures in the figures only represent particular, non-limiting embodiments of the invention which have the purpose of being only illustrative examples of the invention. The description below, even though it makes reference to the figures, is to be understood in a broad sense and includes any deviation from the described embodiments which is obvious to a person skilled in the art. The term "focussing lens" ~~according to claim 1~~ refers to any lens that is capable of providing a focussing electric field for focussing a beam of charged particles like, e.g. an electron beam or an ion beam, onto a specimen. The term "focussing lens" also includes lenses which are combined with means providing a magnetic focussing field.

In the Abstract:

Please add the following Abstract as page 29:

ABSTRACT

A focussing lens for focussing a charged particle beam onto a specimen at a predetermined landing angle. The focussing lens comprises at least one first electrode having a first aperture to generate a focussing electric field for focussing the charged particle beam onto the specimen and a correcting electrode having a curved surface to compensate for landing angle dependent distortions of the focussing electric field caused by the specimen. With the curved surface of the correcting electrode, it is possible to improve the focussing of a charged particle beam at landing angles that differ from the perpendicular landing angle.